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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Nobuyuki MISE et al.  
Serial No.: 10/090,761  
Filed: March 6, 2002  
For: **ETCHING METHOD OF HARDLY-ETCHED MATERIAL AND  
SEMICONDUCTOR FABRICATING METHOD AND  
APPARATUS USING THE METHOD**  
Group: 1765  
Examiner: Lan Vinh

AMENDMENT

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

June 24, 2004

Sir:

In response to the Office Action (Paper No. 031804) dated on March 24,  
2004, please amend the above-identified application as follows.

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 11 of this paper.